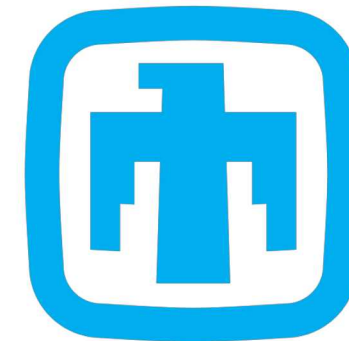


Non-linear Thermal Resistance Trend with Increasing Bilayer Density

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David Guzman³, Samuel Temple Reeve⁴, Alejandro Strachan²,
Paul G. Kotula¹, David P. Adams¹, and Thomas E. Beechem^{1,5}

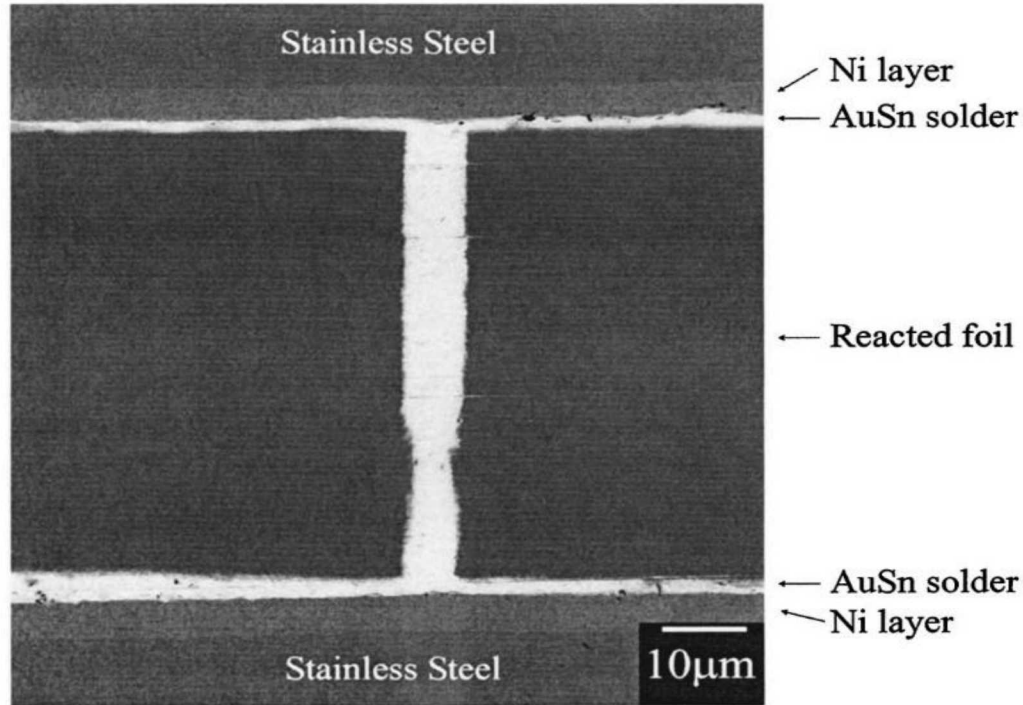
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Reactive metal multilayers (RMM)



SEM micrograph of stainless steel components joined using reactive Al/Ni foils and AuSn solder [3]

Potential applications

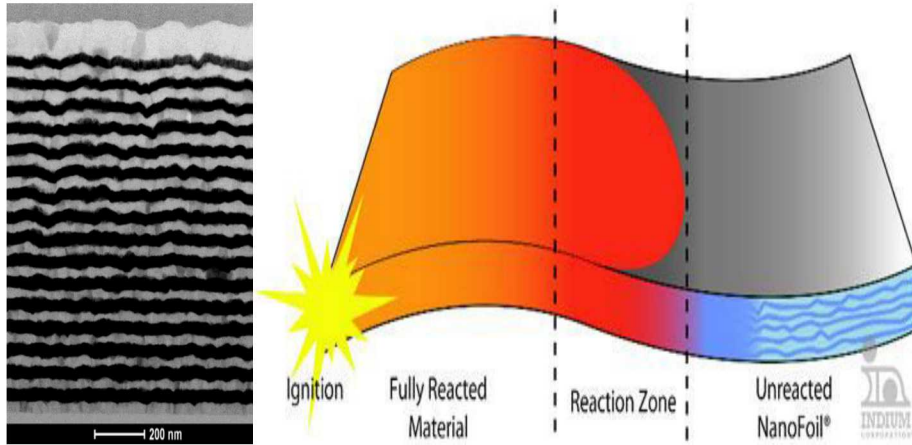
- Heat source for thermal battery [1]
- Lead-free soldering [2]
- Lead-free explosive primers [3]
- Metallic glass welding [4]



[5] EmpaChannel,
<https://www.youtube.com/watch?v=1ti4JJR3piQ>

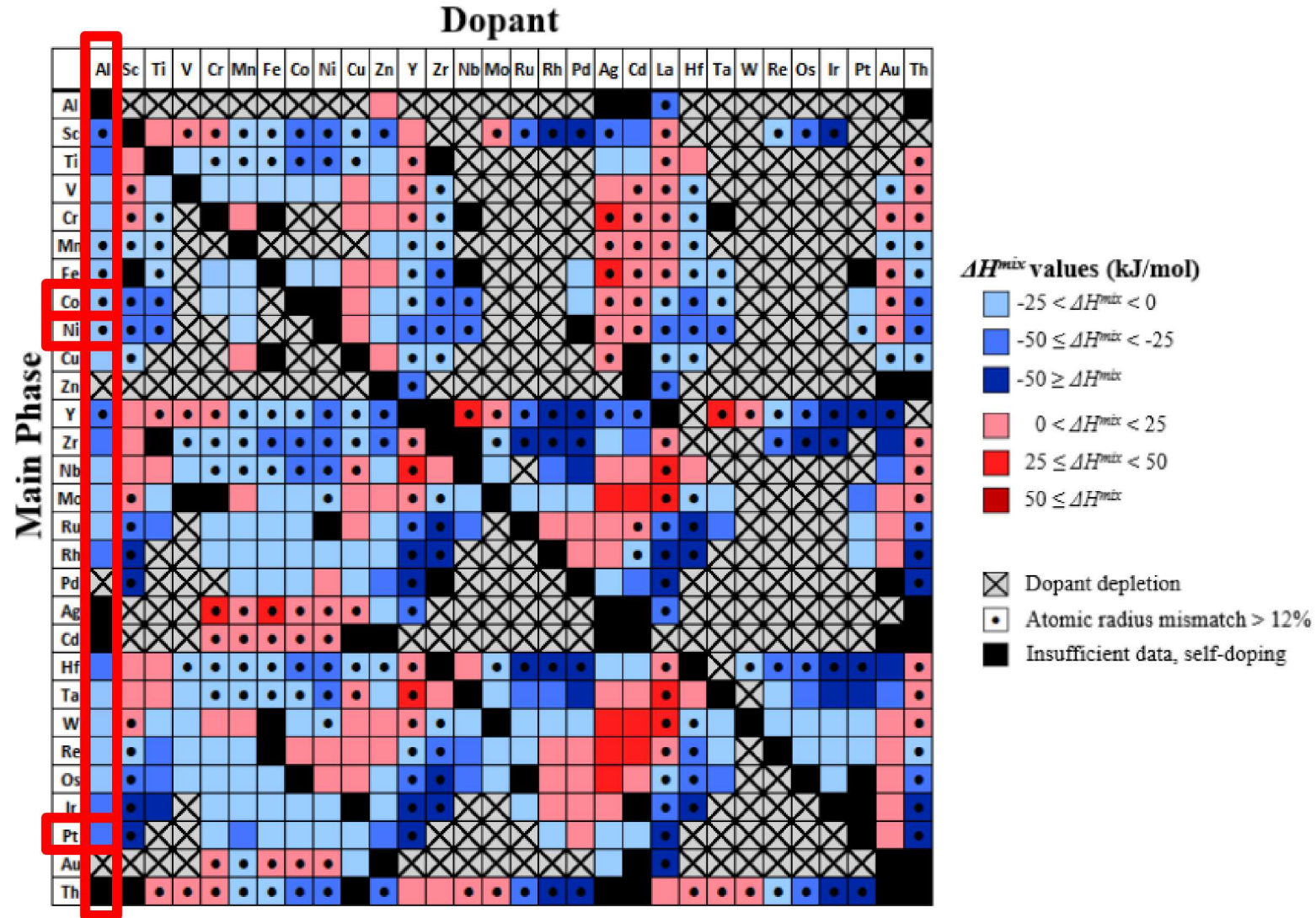
- [1] J. L. Prentice United States Patent No. 4,158,084, 1979
- [2] J. Wang et al., Applied Physics Letters, 2003
- [3] K. T. Higa, Journal of Propulsion and Power, 2007
- [4] A. J. Swiston et al Acta Materialia, 2005

Material selection for mixing reactions



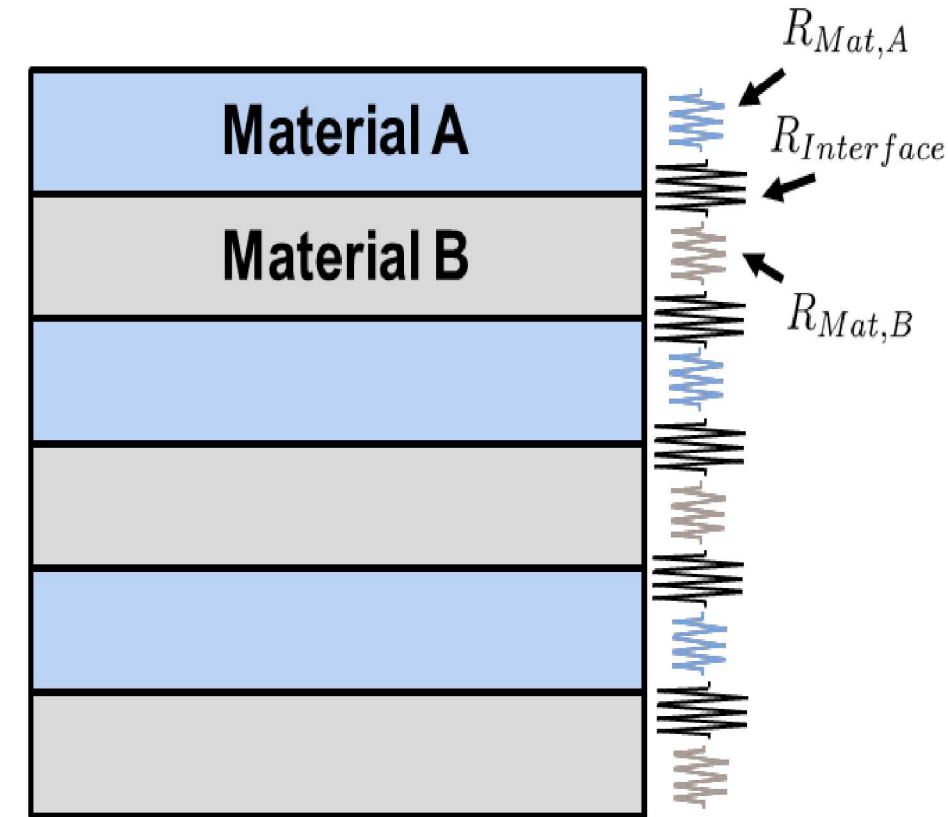
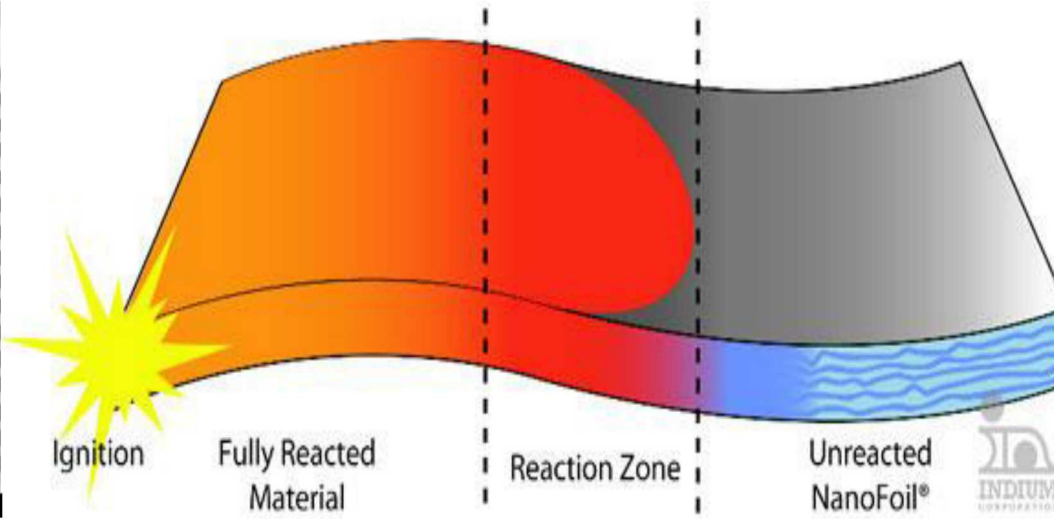
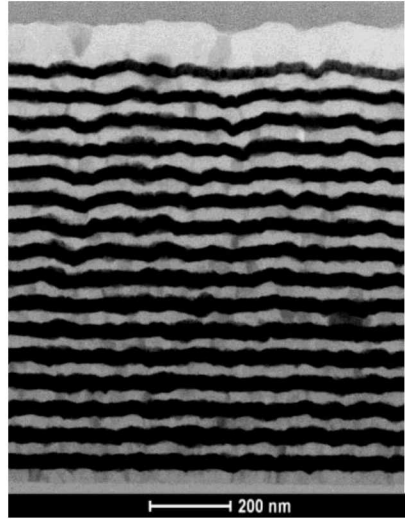
Material selection limitations:

- Adiabatic rxn must exceed melting point of product
- Thermal conductivity must be mitigated
- Activation energy barriers



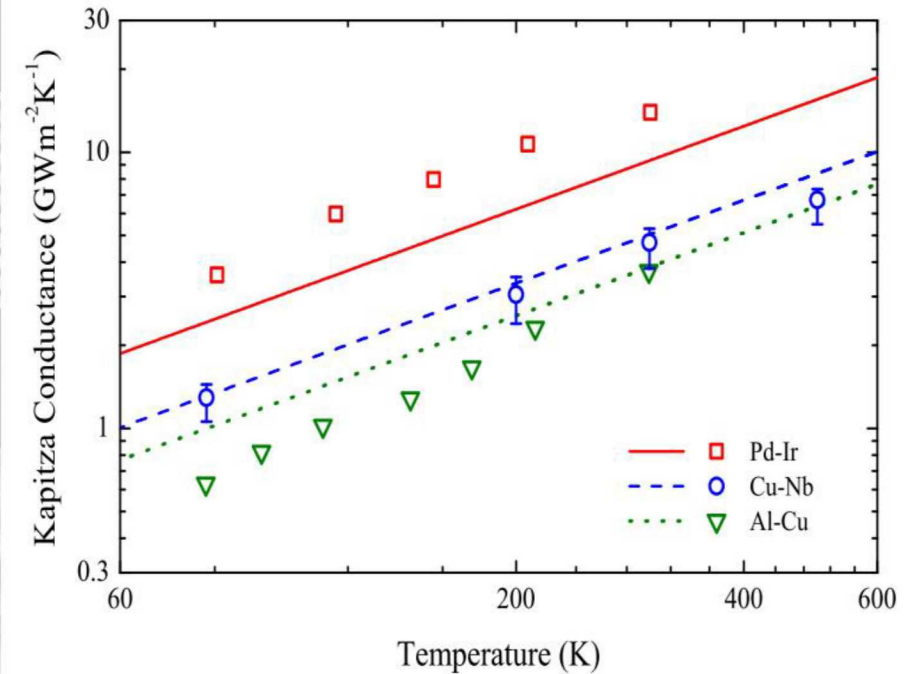
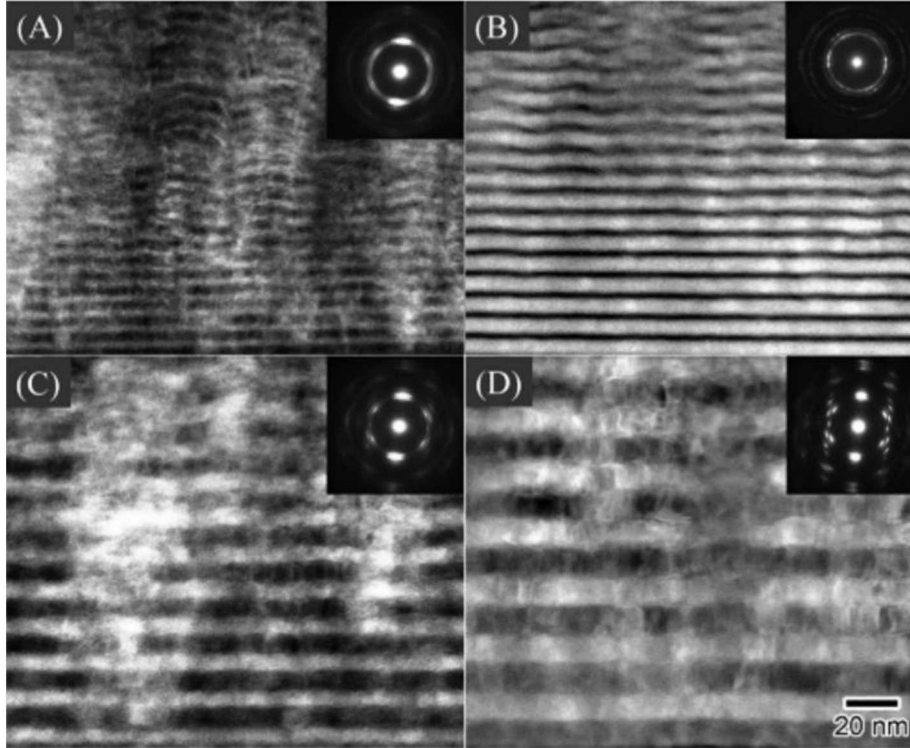
[6] Schuler & Rupert. *Acta Materialia*. 2017

Series lumped resistor model



$$R_{Tot} = R_{Mat,A} + R_{Mat,B} + nR_{Interface} \quad \zeta_{1 \rightarrow 2} = \frac{D(\epsilon_{F,2})\nu_{F,2}}{D(\epsilon_{F,2})\nu_{F,2} + D(\epsilon_{F,1})\nu_{F,1}}$$

Electron diffuse mismatch model - EDMM



[Left] HAADF STEM images for Cu-Nb multilayers with periodicity lengths (thickness of Cu+Nb) (A) 5.4 ± 0.5 nm (B) 8.4 ± 1.1 nm (C) 12.5 ± 1.4 nm (D) 21.4 ± 2.0 nm [Right] Kapitza conductance data and EDMM calculations given by EDMM for Cu-Nb [6], Al-Cu [7], and Ir-Pd [8] versus temperature

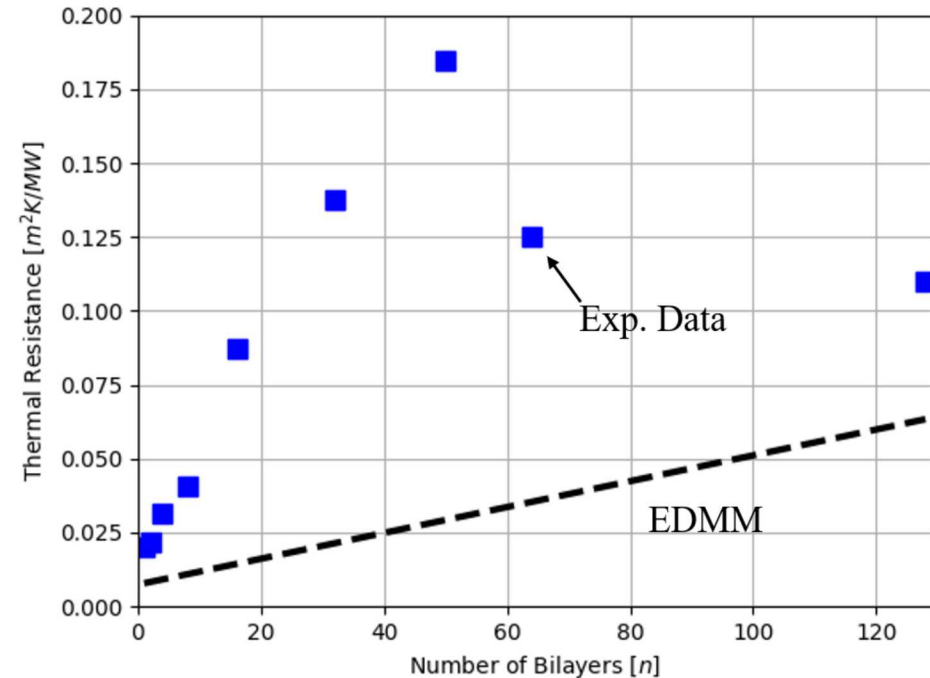
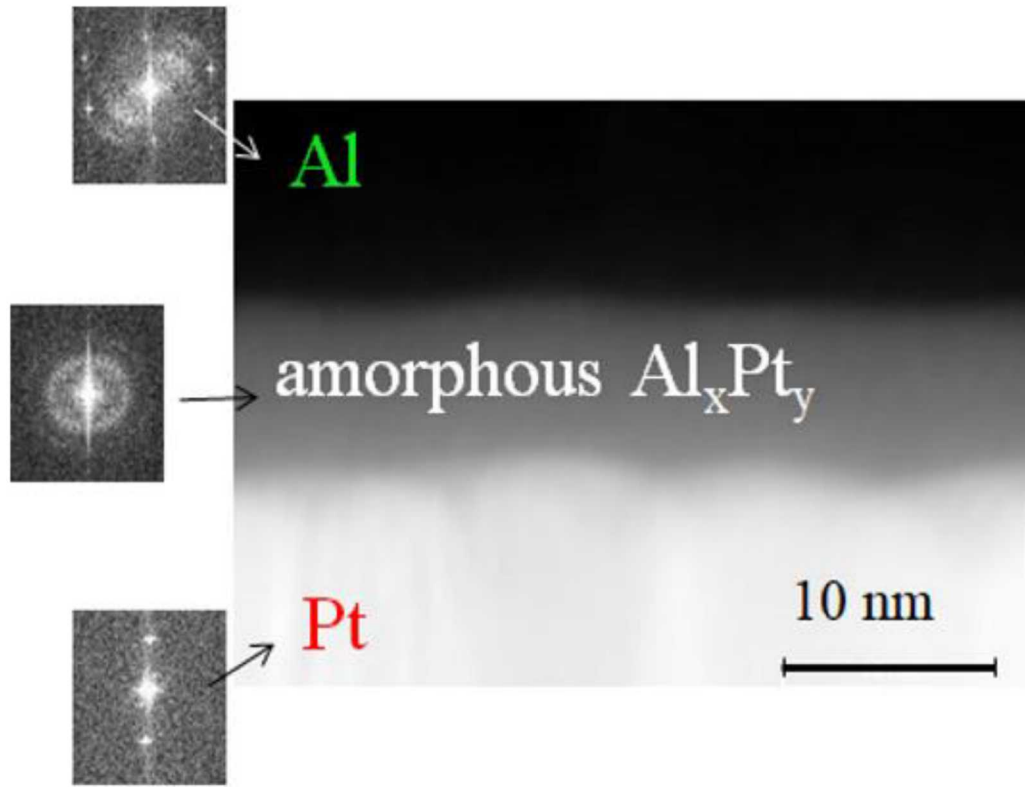
$$R_{tot} = R_0 + \frac{n}{h_{1 \rightarrow 2}}$$

[7] R. Cheaito et al., Applied Physics Letters, 2015

[8] C. Gundrum et al., Phys. Rev. B, 2005

[9] R. B. Wilson and D. G. Cahill, Phys. Rev. Lett., 2012

Nonlinear trends with increasing bilayer density



[Left] TEM image of a 10 nm Al/Pt interface with diffraction patterns quantifying crystallinity and amorphous regions. [Right] SNL experimental resistance of Al/Pt RMM compared with EDMM approximation

$$R_{Tot} = R_{Mat,A} + R_{Mat,B} + nR_{Interface}$$

[10] D. P. Adams, Thin Solid Films 2015.

First principles calculations - TranSiesta

Previous work modeling amorphous transport

- Boltzmann transport equation [10]
 - High cost
 - Difficult to parameterize

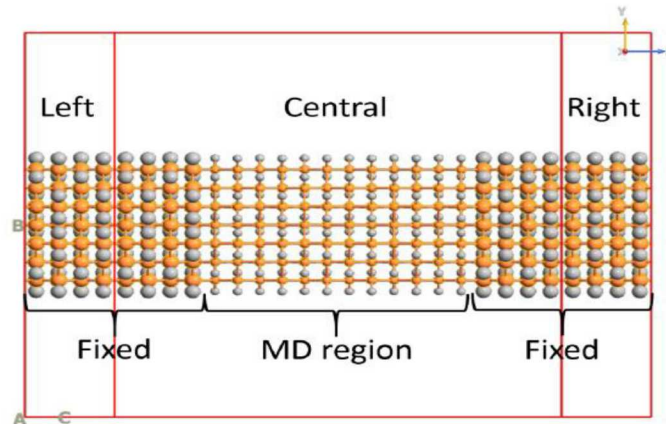
Alternatively

- Length dependent MD-Landauer approach [11]
- Electron-phonon scattering from averaged collective transmission

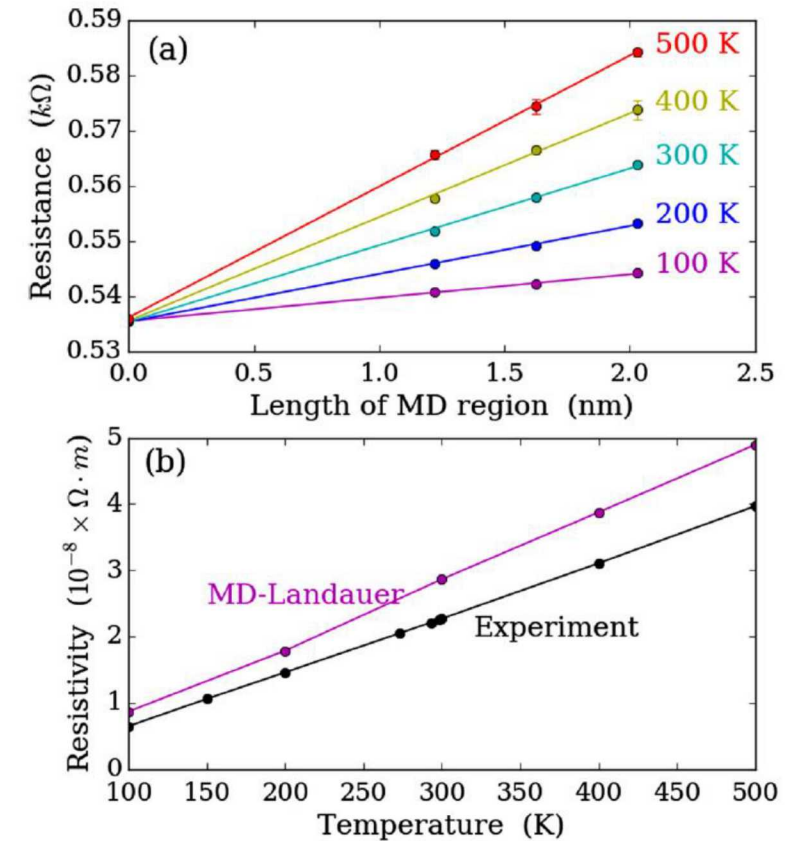
$$G = \frac{1}{R} = G_0 \int T(\varepsilon) \left(-\frac{\partial f}{\partial \varepsilon} \right) d\varepsilon$$

Electronic conductance

$$AR = \rho L$$



MD-Landauer device for transport calculations



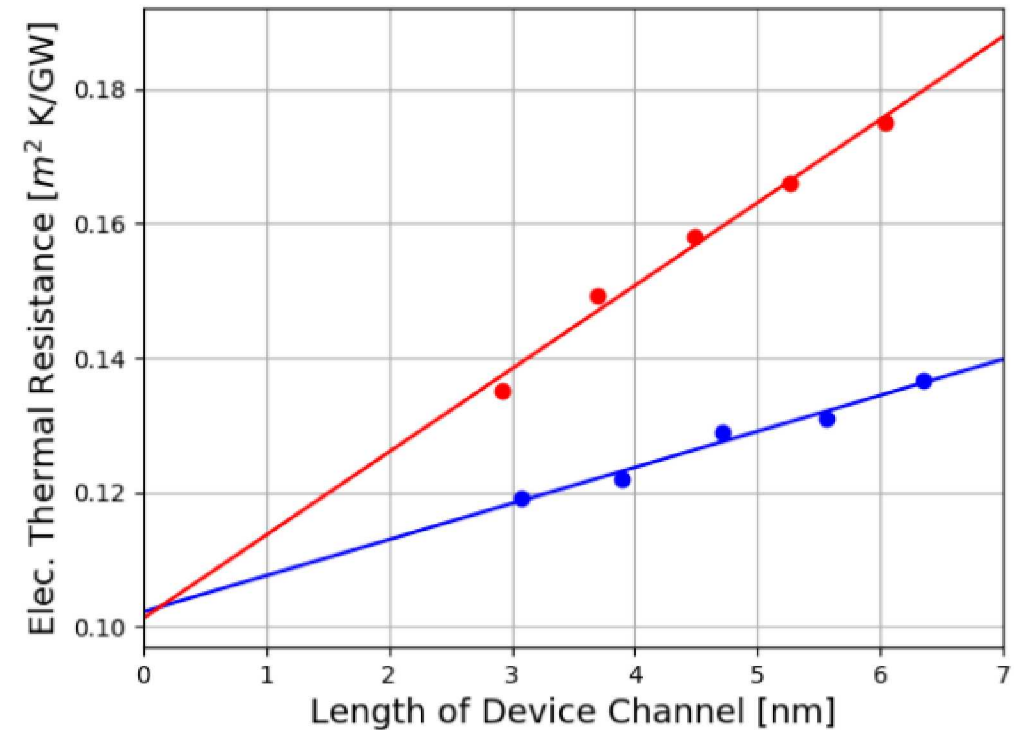
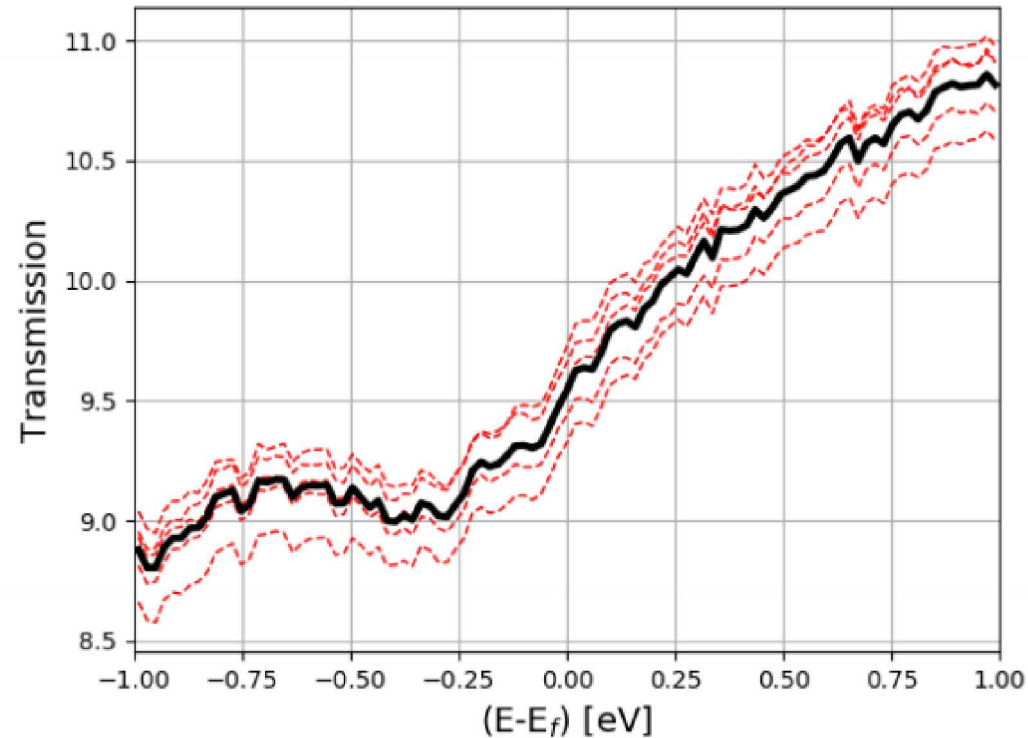
MD-Landauer calculations for bulk Au devices. Resistivity taken from slope of R vs. L.

[10] C. H. Park et al., Nano Letters, 2014

[11] T. Markussen et al., Physical Review B, 2017

First principles calculations: MD-Landauer

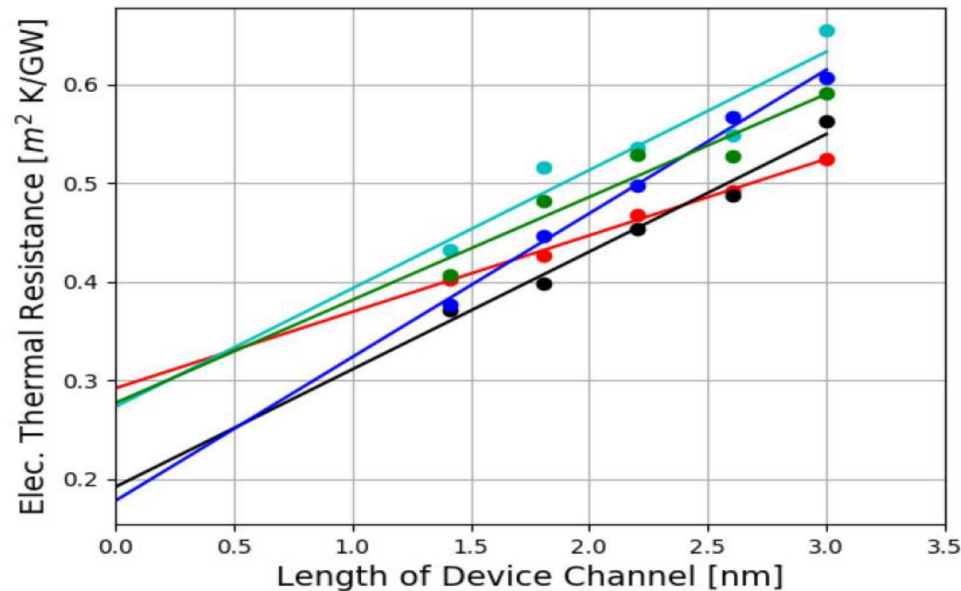
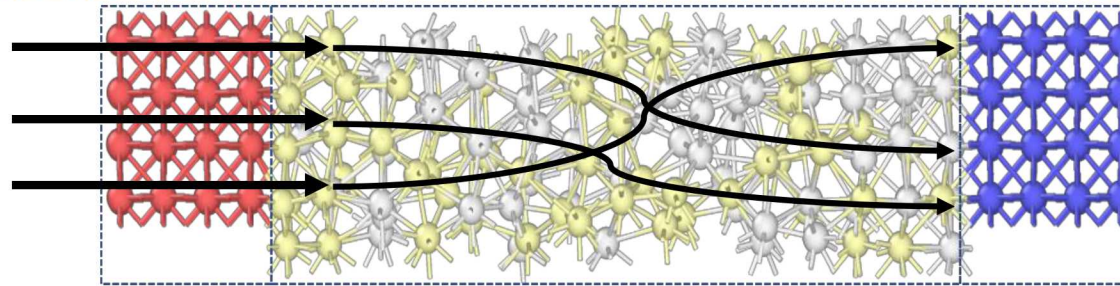
$$G = \frac{1}{R} = G_0 \int T(\varepsilon) \left(-\frac{\partial f}{\partial \varepsilon} \right) d\varepsilon$$



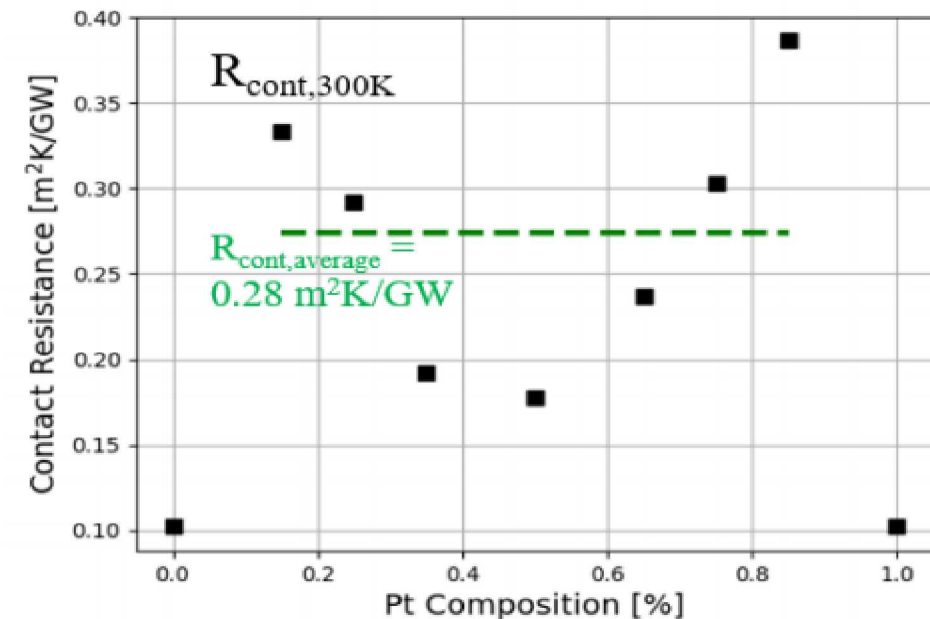
[Left] Crystalline Al transmission spectra at 300K. N = 5.

[Right] Length dependent resistance for Al (blue) and Pt (red) at 300 K. Calculated thermal conductivity of Al = 185 W m⁻¹ K⁻¹ and Pt = 76 W m⁻¹ K⁻¹

First principles calculations: MD-Landauer

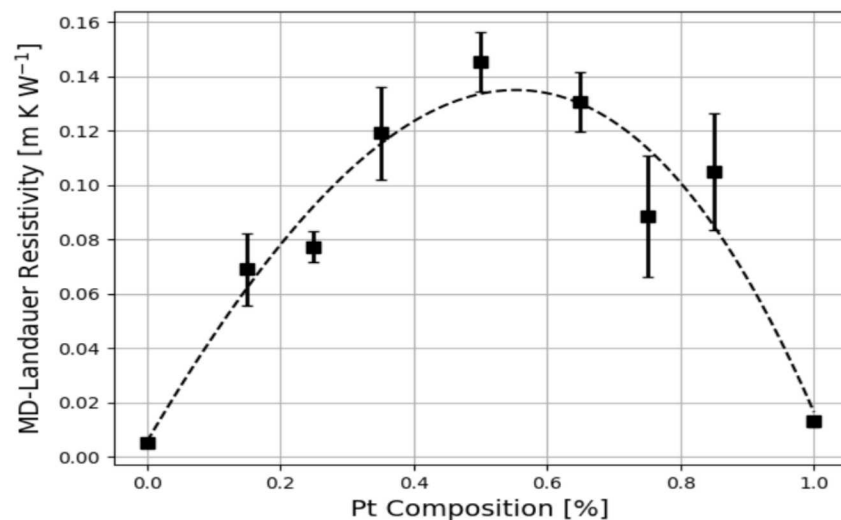
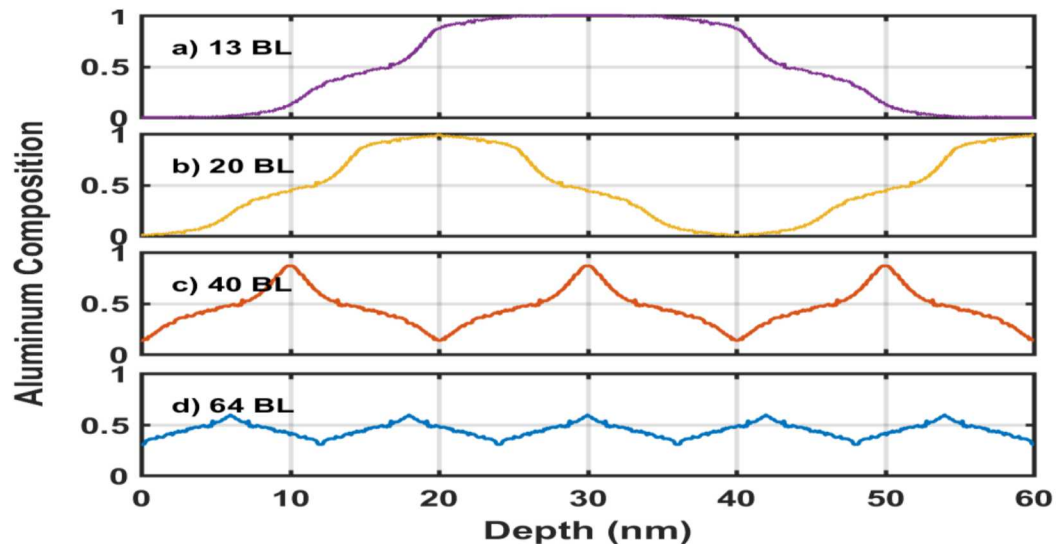


Length dependent device thermal resistance for Al/Pt alloy at 300K. 25% Pt = red, 35% Pt = black, 50 % Pt = blue, 65%, Pt = cyan, 75% Pt = green

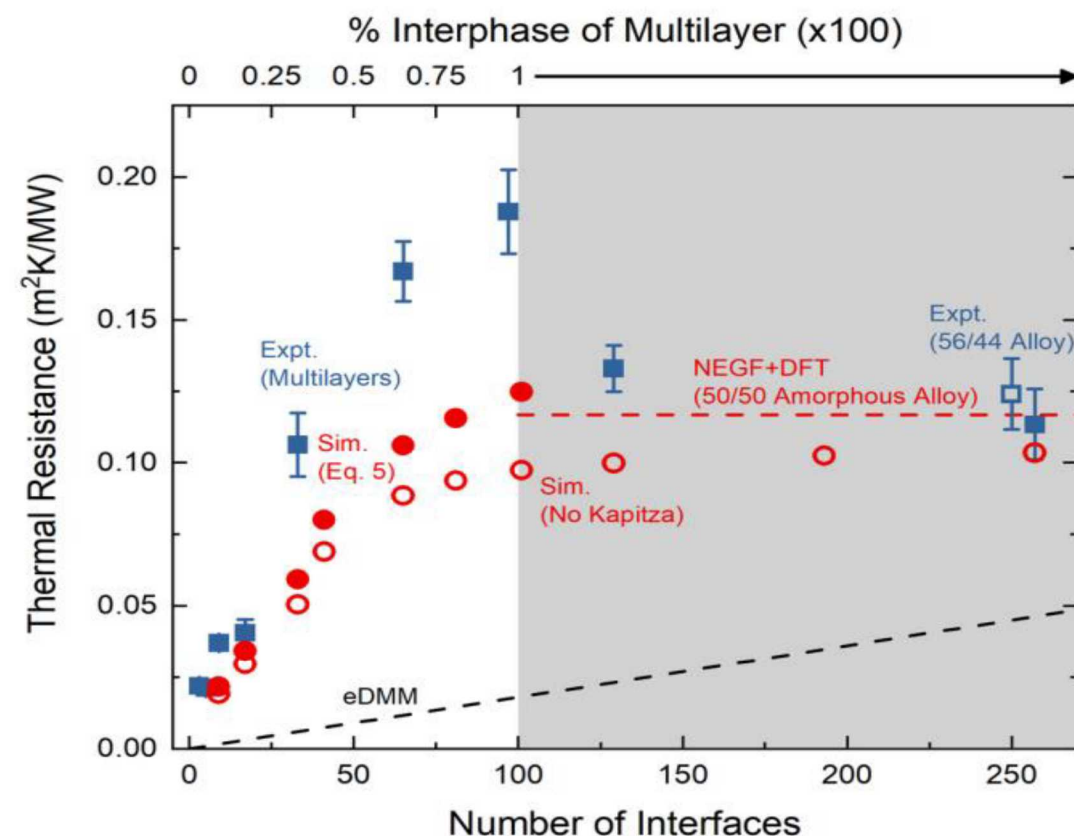


Compositional dependence of contact resistance. End points are fully crystalline Al/Pt devices with identical atom type leads.

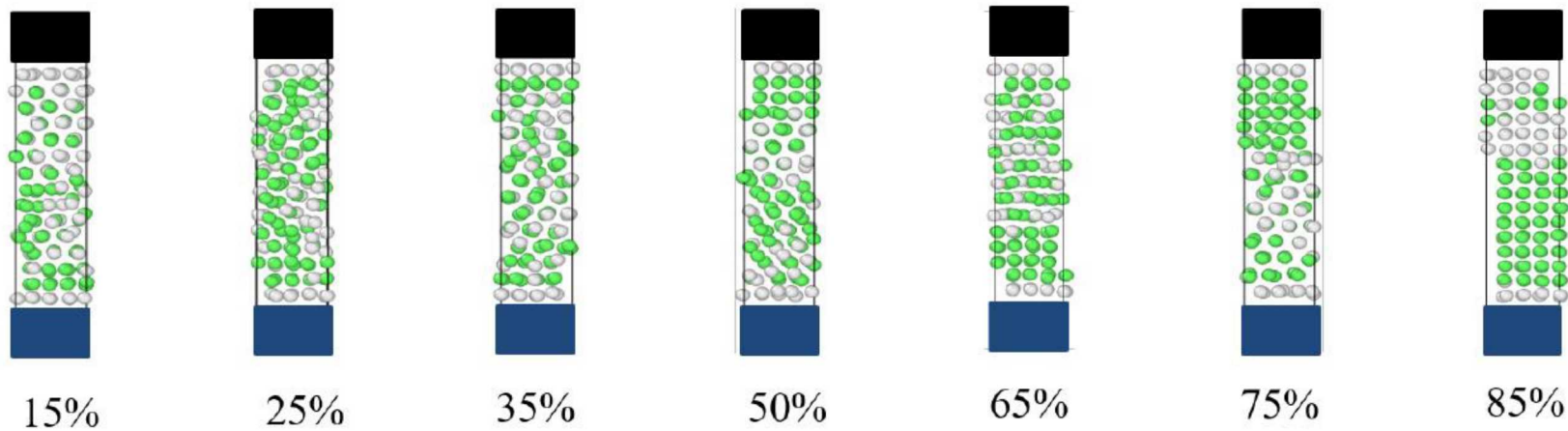
Capturing the roll-over effect



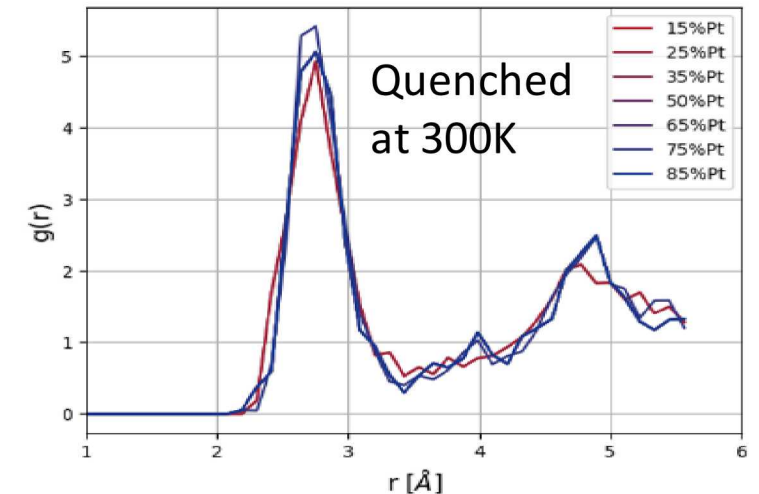
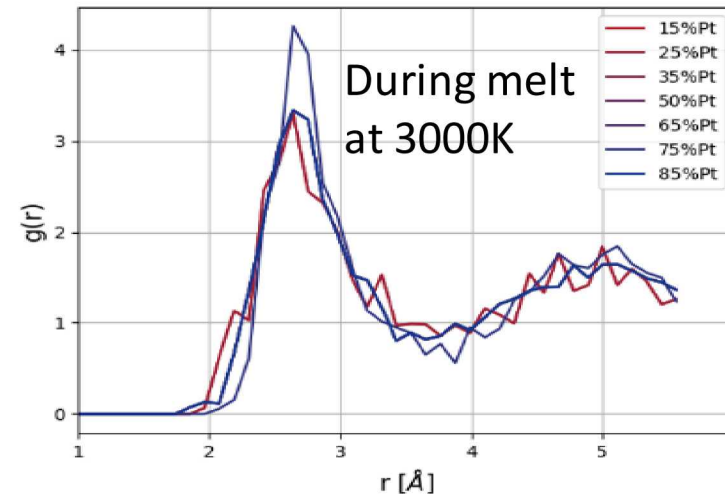
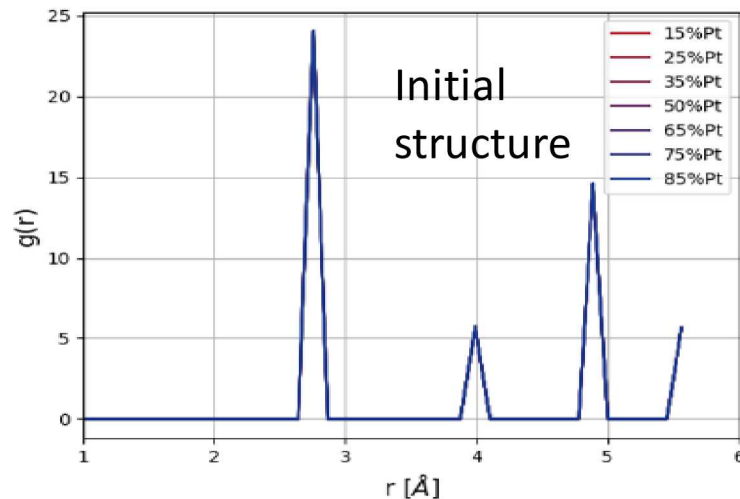
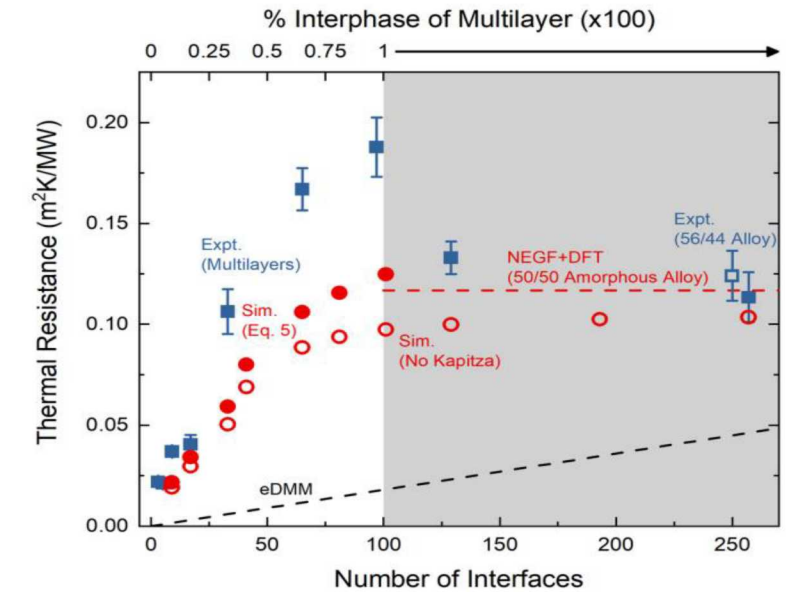
$$R_{BD,NEGF+DFT} = \sum_i^n \frac{d_i}{\kappa(x_i)} + R_{Kapitza}$$



How amorphous is amorphous? Explanations of underestimation

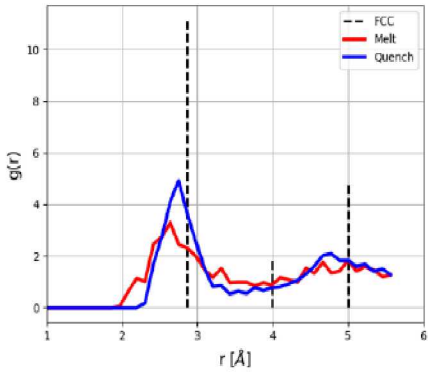


Pt content

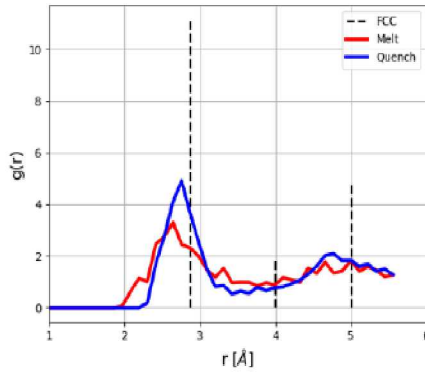


How amorphous is amorphous? Explanations of underestimation

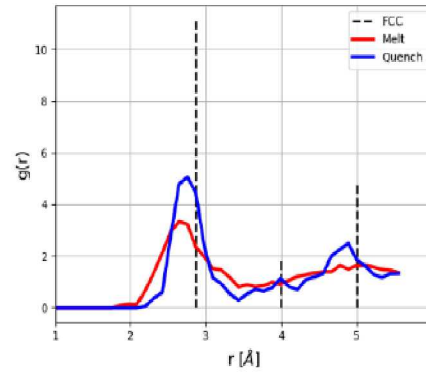
15% Pt



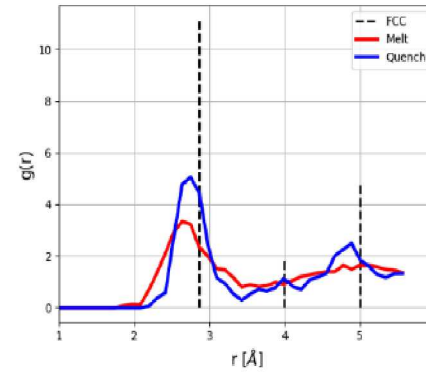
25% Pt



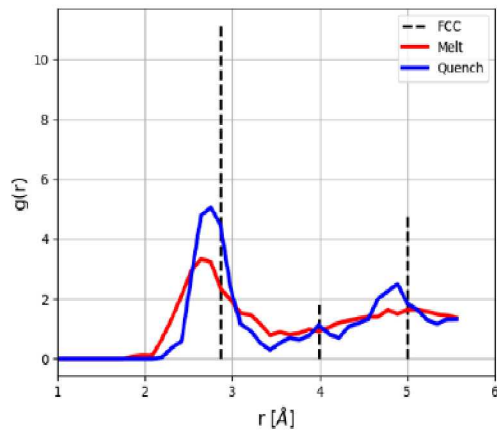
35% Pt



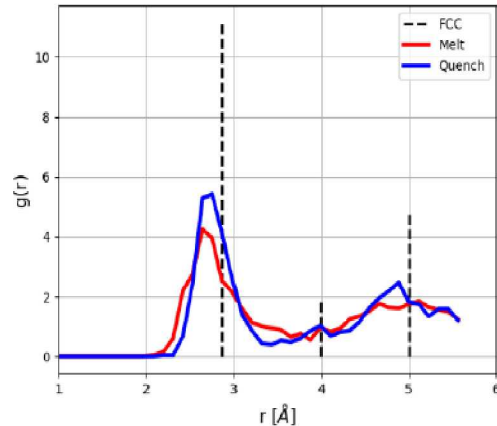
50% Pt



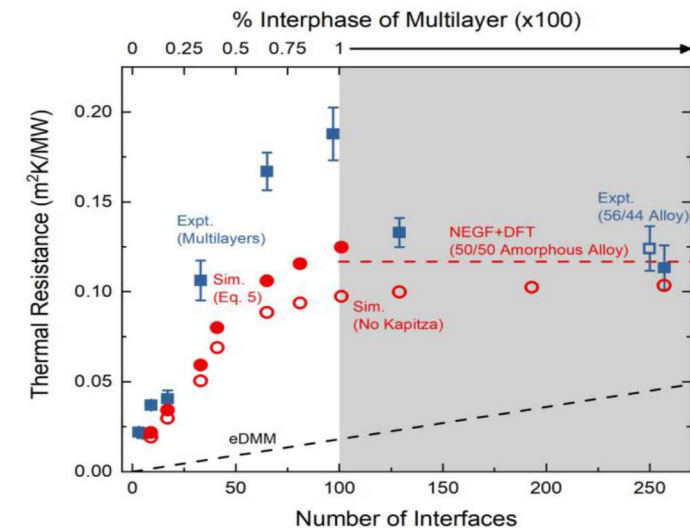
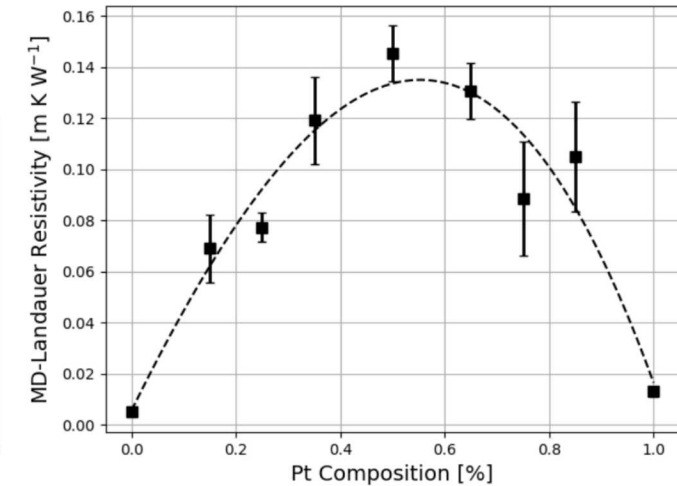
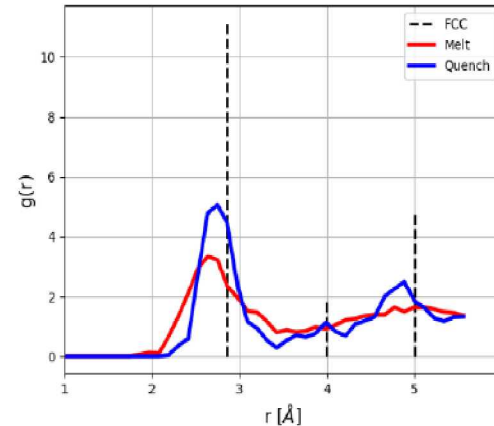
65% Pt



75% Pt



85% Pt



Conclusions and Remarks

- Al/Pt multilayers
 - Excellent heat of mixing
 - Amorphous layer acts at 3rd resistor in series model
 - Critical thickness for maximum resistance
- MD-DFT modeling
 - Accurately predict thermal transport properties of individual amorphous alloy compositions
 - Successfully capture roll-over effects through addition of contact resistance for compositions
 - Complexity of gradients, crystalline phases, and interacting effects not yet captured in model

Acknowledgements

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- Purdue RCAC Computing resources
- Materials Engineering department at Purdue
- Strachan research group (current and prior members)